

Schedule by Room (I)

Room	March 14 (Tue.)		March 15 (Wed.)		March 16 (Thu.)		March 17 (Fri.)	
	AM	PM	AM	PM	AM	PM	AM	PM
MH (Main Hall)	994	13:00 ~ 18:10 SP3 Toward KINTOUN - tasks for autonomous driving and request. to applied physics -		13:45 ~ 17:30 S25 Innovation Inspired by Informatics in Crystal Growth Processes		13:00 ~ 17:55 SP5 Healthy life and applied physics		13:00 ~ 17:00 SP6 Revisiting Research Evaluation Methods: Applied Physics and Future Society
211 (211+212)	122	10:00 ~ 12:00 3.9 Terahertz technologies	09:00 ~ 12:30 3.9 Terahertz technologies	13:30 ~ 18:15 16.3 Bulk, thin-film and other silicon-based solar cells	09:45 ~ 11:15 16.3 Bulk, thin-film and other silicon-based solar cells	13:15 ~ 18:15 16.3 Bulk, thin-film and other silicon-based solar cells	09:45 ~ 11:45 16.3 Bulk, thin-film and other silicon-based solar cells	13:30 ~ 16:45 16.3 Bulk, thin-film and other silicon-based solar cells
213	60	09:00 ~ 12:15 6.4 Thin films and New materials	09:00 ~ 12:15 3.5 Laser system and materials	13:15 ~ 14:15 CS.9 3.5/3.14 Code-sharing session	09:30 ~ 11:30 16.1 Fundamental properties, evaluation, process and devices in disordered materials	13:45 ~ 17:30 16.1 Fundamental properties, evaluation, process and devices in disordered materials		
301	270	13:00 ~ 18:00 SP2 Evolution to IRDS/SDR from ITRS/STRJ	09:00 ~ 10:45 8.2 Plasma measurements and diagnostics	13:30 ~ 13:45 8.10 Plasma Electronics Award Ceremony	09:30 ~ 11:30 CS.3 6.6/12.2 Code-sharing session	13:15 ~ 18:30 S9 The role of functional oxides in the next-generation neuromorphic hardware	09:00 ~ 12:15 15.6 Group IV Compound Semiconductors (SiC)	13:45 ~ 17:00 15.6 Group IV Compound Semiconductors (SiC)
302	270	13:15 ~ 18:00 12.4 Organic light-emitting devices and organic transistors	11:00 ~ 11:30 8.9 Plasma Electronics Invited Talk	13:45 ~ 18:15 S12 The research forefront of plasma processing technology for energy related materials	09:00 ~ 12:00 12.4 Organic light-emitting devices and organic transistors	13:15 ~ 18:45 S16 Current Status and Future Issues on Organic Transistors for Printed Electronics	13:15 ~ 17:00 12.4 Organic light-emitting devices and organic transistors	
303	220	09:00 ~ 11:45 12.5 Organic solar cells	09:30 ~ 11:45 6.6 Probe Microscopy	13:30 ~ 18:00 12.5 Organic solar cells	09:00 ~ 12:15 12.5 Organic solar cells	13:15 ~ 16:30 S22 Automotive MEMS devices and related technologies for autonomous cruising	09:00 ~ 13:30 12.5 Organic solar cells	
304	220	09:15 ~ 12:00 13.4 Si wafer processing /Si based thin film /Interconnect technology/ MEMS/ Integration technology	09:00 ~ 11:30 13.4 Si wafer processing /Si based thin film /Interconnect technology/ MEMS/ Integration technology	13:15 ~ 18:00 S20 Highly reliable metallization technology for long term retention	09:15 ~ 11:30 S28 Photovoltaic 4.0 - Next-generation renewable energy systems powered by high-efficiency, low-cost photovoltaics -	13:00 ~ 18:00 S28 Photovoltaic 4.0 - Next-generation renewable energy systems powered by high-efficiency, low-cost photovoltaics -	13:00 ~ 17:00 CS.2 6.1/13.3/13.5 Code-sharing Session	
311	70	09:00 ~ 12:15 12.2 Characterization and Materials Physics	09:00 ~ 12:00 12.2 Characterization and Materials Physics	13:15 ~ 18:15 6.4 Thin films and New materials	09:00 ~ 12:00 3.6 Ultrashort-pulse and high-intensity lasers	13:15 ~ 19:00 3.6 Ultrashort-pulse and high-intensity lasers		
312	70		09:30 ~ 11:30 3.1 Basic optics and frontier of optics	13:15 ~ 16:00 3.1 Basic optics and frontier of optics		13:15 ~ 14:30 11.4 Analog applications and their related technologies		

Schedule by Room (II)

Room	Cap.	March 14 (Tue.)		March 15 (Wed.)		March 16 (Thu.)		March 17 (Fri.)	
		AM	PM	AM	PM	AM	PM	AM	PM
313 (313+314)	134	09:00 ~ 12:15 12.1 Fabrications and Structure Controls	13:30 ~ 18:00 12.1 Fabrications and Structure Controls	09:00 ~ 12:00 15.3 III-V-group epitaxial crystals, Fundamentals of epitaxy	13:15 ~ 18:30 S19 English session: Joint Symposium on Nanobiotechnology and Biosensing	09:00 ~ 12:15 8.6 Plasma life sciences	13:45 ~ 17:00 8.6 Plasma life sciences	09:00 ~ 11:30 8.4 Plasma etching	12:45 ~ 17:00 8.7 Plasma phenomena, emerging area of plasmas and their new applications
315	168	09:30 ~ 11:45 13.8 Compound and power electron devices and process technology	13:15 ~ 17:15 13.8 Compound and power electron devices and process technology	09:00 ~ 11:45 13.8 Compound and power electron devices and process technology	13:15 ~ 17:45 13.8 Compound and power electron devices and process technology	09:00 ~ 11:30 8.5 Plasma nanotechnology 11:30 ~ 12:15 8.8 Plasma Electronics English Session	13:15 ~ 18:00 S23 Recent GFIS microscopy technology and its future prospects for R & D of materials and devices	09:00 ~ 13:00 8.3 Plasma deposition of thin film and surface treatment	14:00 ~ 17:00 8.1 Plasma production and control
316	47		13:15 ~ 17:45 6.5 Surface Physics, Vacuum		13:15 ~ 17:15 11.5 Junction and circuit fabrication process, digital applications	09:00 ~ 12:00 3.14 Optical control devices and optical fibers	13:45 ~ 15:30 3.14 Optical control devices and optical fibers		
317	47		13:15 ~ 16:00 1.3 Novel technologies and interdisciplinary engineering		13:00 ~ 16:45 11.1 Fundamental properties	09:30 ~ 11:45 11.1 Fundamental properties			
318	49	09:30 ~ 11:45 15.5 Group IV crystals and alloys	13:45 ~ 16:00 15.5 Group IV crystals and alloys	09:00 ~ 12:00 CS. 4. 7. Code-sharing Session: Beam Technology and Nanofabrication	13:15 ~ 16:15 CS. 4. 7. Code-sharing Session: Beam Technology and Nanofabrication	09:00 ~ 12:00 11.2 Critical Current, Superconducting Power Applications	13:15 ~ 17:30 11.2 Thin and thick superconducting films, coated conductors and film crystal growth		
411	72	09:15 ~ 11:45 13.9 Optical properties and light-emitting devices	13:15 ~ 17:00 13.9 Optical properties and light-emitting devices	09:15 ~ 11:45 13.9 Optical properties and light-emitting devices	13:15 ~ 17:30 13.9 Optical properties and light-emitting devices		16:00 ~ 18:30 6.1 Ferroelectric thin films	09:00 ~ 12:00 6.1 Ferroelectric thin films	
412	72	09:00 ~ 12:15 6.2 Carbon-based thin films	13:15 ~ 18:15 6.2 Carbon-based thin films	09:00 ~ 11:45 6.2 Carbon-based thin films	13:15 ~ 18:15 6.2 Carbon-based thin films	09:00 ~ 12:15 13.5 Semiconductor devices and related technologies	13:15 ~ 18:30 13.5 Semiconductor devices and related technologies		
413	103	09:00 ~ 12:10 Tutorial	13:15 ~ 18:30 S3 Recent progress of Nano-Material Optical-Manipulation	09:00 ~ 12:10 Tutorial	13:15 ~ 17:15 S5 Recent optical bio-sensing in a microscopic region	09:00 ~ 12:15 13.3 Insulator technology	14:00 ~ 17:00 13.3 Insulator technology	09:00 ~ 11:45 3.4 Biomedical optics	13:15 ~ 16:00 3.4 Biomedical optics
414 (414+415)	150	09:30 ~ 11:30 6.6 Probe Microscopy	13:15 ~ 17:45 6.6 Probe Microscopy	09:00 ~ 12:10 Tutorial	13:15 ~ 16:15 S21 Electronics is still fantastical ~ Learn the present of electronic industry and active carrier selection form main players pulling the world~	09:00 ~ 11:30 12.1 Fabrications and Structure Controls	13:15 ~ 18:00 S13 Emerging trends in energy harvesting: Toward Internet of Things	09:00 ~ 12:15 3.10 Optical quantum physics and technologies	13:15 ~ 17:00 3.10 Optical quantum physics and technologies
416 (416+417)	150	09:00 ~ 12:10 Tutorial	13:15 ~ 18:00 S4 Quantum Cryptography - securing our future society	09:00 ~ 11:45 12.3 Functional Materials and Novel Devices	13:15 ~ 17:45 S17 Soft Robots ~towards integration and linkage among materials, electronics, and mechanics~	09:00 ~ 11:45 12.3 Functional Materials and Novel Devices	13:15 ~ 18:15 12.3 Functional Materials and Novel Devices		13:15 ~ 15:45 12.3 Functional Materials and Novel Devices

Schedule by Room (III)

Room	Cap.	March 14 (Tue.)		March 15 (Wed.)		March 16 (Thu.)		March 17 (Fri.)	
		AM	PM	AM	PM	AM	PM	AM	PM
418	124	11:00~11:30 JSAP Young Scientist Presentation Award Ceremony 11:30~11:40 Exhibition Award Ceremony	17:00~18:15 JSAP Outstanding Achievement Award Ceremony	09:00 ~ 12:10 Tutorial	13:30 ~ 18:30 S6 Variety of light sources and possibilities of their applications to novel light processing S7 Recent Progress and Future Perspective on Vacuum Technology for Accelerator and Space Sciences	09:00 ~ 11:45 3.8 Optical measurement, instrumentation, and sensor	13:15 ~ 17:45 3.8 Optical measurement, instrumentation, and sensor	09:00 ~ 11:45 3.8 Optical measurement, instrumentation, and sensor	13:15 ~ 16:45 3.8 Optical measurement, instrumentation, and sensor
419	124	09:00 ~ 11:30 6.3 Oxide electronics	13:30 ~ 18:00 6.3 Oxide electronics	09:00 ~ 11:30 6.3 Oxide electronics	13:15 ~ 17:30 S7 Recent Progress and Future Perspective on Vacuum Technology for Accelerator and Space Sciences	09:00 ~ 12:15 6.3 Oxide electronics	13:30 ~ 16:40 Tutorial	09:00 ~ 12:15 6.3 Oxide electronics	13:30 ~ 16:00 6.3 Oxide electronics
421	50	13:15 ~ 16:30 9.1 Dielectrics, ferroelectrics	13:15 ~ 18:15 9.2 Nanowires and Nanoparticles	09:00 ~ 12:15 9.2 Nanowires and Nanoparticles	13:15 ~ 18:15 9.2 Nanowires and Nanoparticles	09:00 ~ 11:45 3.16 Optics and Photonics English Session			
422	50			09:00 ~ 12:15 3.13 Semiconductor optical devices	13:15 ~ 17:45 3.13 Semiconductor optical devices	09:00 ~ 11:30 3.13 Semiconductor optical devices	13:15 ~ 16:30 3.2 Equipment optics and materials		
423	50	13:15 ~ 17:00 CS.4.7. Code-sharing Session: Beam Technology and Nanofabrication		09:00 ~ 11:30 CS.4.7. Code-sharing Session: Beam Technology and Nanofabrication	13:15 ~ 16:15 S1 How can we express the interest of physics for pupils and students? ~centering around the class relate to atomic physics~	09:00 ~ 12:15 1.5 Instrumentation, measurement and Metrology			
424	48	13:15 ~ 17:30 CS.4.7. Code-sharing Session: Beam Technology and Nanofabrication		13:15 ~ 18:30 1.4 Energy conversion, storage, resources and environment	13:15 ~ 18:30 1.4 Energy conversion, storage, resources and environment	10:00 ~ 12:00 CS.4.7. Code-sharing Session: Beam Technology and Nanofabrication	14:00 ~ 16:00 CS.4.7. Code-sharing Session: Beam Technology and Nanofabrication		
501	264	09:00 ~ 12:00 10.3 Spin devices, magnetic memories and storages 14:45 ~ 15:45 10.4 Semiconductor spintronics, superconductor, multiferroics	13:00 ~ 14:30 10.3 Spin devices, magnetic memories and storages 14:45 ~ 15:45 10.4 Semiconductor spintronics, superconductor, multiferroics	09:00 ~ 12:00 10.4 Semiconductor spintronics, superconductor, multiferroics	13:15 ~ 18:30 CS.6.10.1/10.2/10.3/10.4 Code-sharing session	09:00 ~ 12:00 10.2 Fundamental and exploratory device technologies for spin	13:45 ~ 17:00 S14 Frontier of spintronic transport devices: their recent advances and applications	09:00 ~ 12:15 10.1 Emerging materials in spintronics and magnetics (including fabrication and characterization methodologies)	13:15 ~ 15:00 10.1 Emerging materials in spintronics and magnetics (including fabrication and characterization methodologies)
502	264	09:30 ~ 12:15 21.1 Joint Session K "Wide bandgap oxide semiconductor materials and devices"	13:45 ~ 17:45 21.1 Joint Session K "Wide bandgap oxide semiconductor materials and devices"	09:00 ~ 12:15 21.1 Joint Session K "Wide bandgap oxide semiconductor materials and devices"	13:45 ~ 18:00 S27 Approaching the Crystal Properties of Metal Oxide	09:00 ~ 12:15 21.1 Joint Session K "Wide bandgap oxide semiconductor materials and devices"	13:45 ~ 18:30 S26 Process technology for advanced power semiconductor devices	09:00 ~ 11:45 21.1 Joint Session K "Wide bandgap oxide semiconductor materials and devices"	
503	300	09:00 ~ 12:15 15.4 III-V-group nitride crystals	13:45 ~ 17:45 S24 Materials Science and Advanced Electronics Created by Singularity of Nitride Semiconductors	09:00 ~ 12:15 15.4 III-V-group nitride crystals	13:45 ~ 18:15 15.4 III-V-group nitride crystals	09:00 ~ 12:15 15.4 III-V-group nitride crystals	13:45 ~ 18:00 15.4 III-V-group nitride crystals	09:00 ~ 12:30 15.4 III-V-group nitride crystals	13:45 ~ 16:30 15.4 III-V-group nitride crystals
512 (511+512)	120	09:00 ~ 12:15 3.7 Laser processing	13:45 ~ 18:00 3.7 Laser processing	09:00 ~ 12:15 3.7 Laser processing	13:30 ~ 18:00 S10 Progress and outlook of nanoimprint technology	09:00 ~ 12:15 S11 Imaging of interfaces in thin films and multilayers	13:45 ~ 17:00 S11 Imaging of interfaces in thin films and multilayers		
513	41	09:00 ~ 11:30 10.5 Application of magnetic field		09:00 ~ 11:15 13.6 Semiconductor English Session				09:00 ~ 12:00 15.2 II-VI and related compounds	
514	41	13:45 ~ 15:45 1.6 Ultrasonics		13:45 ~ 17:45 9.5 New functional materials and new phenomena		09:15 ~ 12:15 1.1 Interdisciplinary and General Physics		09:00 ~ 10:15 16.2 Energy Harvesting	

Schedule by Room (IV)

B5	200	09:00 ~ 12:30	15.3 III-V group epitaxial crystals, Fundamentals of epitaxy	09:00 ~ 12:00	13.2 Exploratory Materials, Physical Properties, Devices	13:45 ~ 17:45	15.3 III-V group epitaxial crystals, Fundamentals of epitaxy
B6	200	09:30 ~ 11:30	2.3 Application, radiation generators, new technology	09:00 ~ 12:00	13:30 ~ 17:45	17.2 Graphene	09:00 ~ 12:00
E204	80	10:00 ~ 12:00	SP4 Promotion of Diversity for Promising Science and Technology	09:30 ~ 12:15	17.2 Graphene	13:30 ~ 17:45	15.3 III-V group epitaxial crystals, Fundamentals of epitaxy
E205	72	09:30 ~ 11:30	2.3 Application, radiation generators, new technology	09:45 ~ 12:30	2.2 Detection systems	13:30 ~ 15:30	2.3 Application, radiation generators, new technology
E206	80	10:00 ~ 12:00	9.3 Nanoelectronics	09:00 ~ 12:15	13.4 Si wafer processing /Si based thin film /Interconnect technology/ MEMS/ Integration technology	13:45 ~ 18:30	13.4 Si wafer processing /Si based thin film /Interconnect technology/ MEMS/ Integration technology
F201	172	09:15 ~ 12:15	15.7 Crystal evaluation, impurities and crystal defects	09:30 ~ 12:30	13.10 Compound solar cells	13:30 ~ 15:15	12.1 Fabrications and Structure Controls
F202	172	09:00 ~ 12:15	3.1.2 Nanoscale optical science and near-field optics	09:00 ~ 12:30	3.11 Photonic structures and phenomena	13:45 ~ 18:00	17.3 Layered materials
F203	174	09:00 ~ 12:30	15.1 Bulk crystal growth	09:00 ~ 12:15	17.3 Layered materials	13:45 ~ 18:45	09:45 ~ 12:15
F204	174	09:00 ~ 12:15	12.7 Biomedical Engineering and Biochips	09:30 ~ 12:15	15.6 Group IV Compound Semiconductors (SiC)	13:30 ~ 19:00	13.45 ~ 17:00
F205	174	13:45 ~ 17:45	3.3 Information photonics and image engineering	09:30 ~ 12:15	3.3 Information photonics and image engineering	13:45 ~ 18:45	09:00 ~ 12:15
F206	174	14:00 ~ 17:45	22.1 Joint Session M "Phonon Engineering"	10:00 ~ 12:15	22.1 Joint Session M "Phonon Engineering"	13:45 ~ 19:00	09:00 ~ 12:15

